## Low-temperature growth of GaInNAs/GaAs quantum wells for 1.3µm lasers using metal-organic vapor-phase epitaxy

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The growth and optimization of GaInNAs/GaAs quantum wells has been a subject of intense research during recent years. These efforts are mainly motivated from the possibility of realizing 1.3-1.55 µm diode lasers on GaAs substrates, opening up a pathway for the development of long-wavelength vertical-cavity lasers (VCLs) as well as low-cost edge-emitting lasers with improved temperatureperformance as compared to the InP-based technology. So far, the most promising results have been obtained using molecular beam epitaxy (MBE), by which both low-threshold edge-emitting lasers and 1.3-um VCLs have been demonstrated [1]. On the other hand, materials grown by metal-organic vaporphase epitaxy (MOVPE) still appear to lag a step behind, generally resulting in higher threshold currents and broader photoluminescence (PL) emission characteristics, although some promising results recently have been reported also in this case [2]. In the present study, GaInNAs QWs have been grown by MOVPE using a systematic variation of growth parameters in the very low temperature regime. It is demonstrated that good material quality can be obtained at temperatures as low as 475-505°C in combination with very low growth rates. However, a complex relation between growth parameters, PL intensity, PL linewidth and broad-area (BA) laser performance has to be considered. We also note and discuss a strong interplay between the different growth parameters that significantly complicates the optimization process, e.g., highlighting the importance of gas-phase pre-reactions.

GaInNAs and InGaAs/GaAs QW structures were grown on (001) oriented GaAs substrates by low-pressure (100mbar) MOVPE using DMHy, TEGa, TMIn, and TBAs as precursors at growth temperatures and growth rates of 475-505°C and 0.03 nm/s, respectively. Table 1 summarizes the different structures and corresponding PL and BA laser results. The PL test structures comprise a single QW embedded under a 100 nm GaAs cap layer and is annealed for 10 min at the growth temperature of the BA laser AlGaAs claddings (670°C). BA lasers with 50 μm stripe widths and different lengths were measured under pulsed conditions at heat sink temperatures between 10 and 80°C.

Figure 1 shows the relation between growth temperature and PL FWHM for 1.3- $\mu$ m SQWs. While the PL peak intensity in this interval decreases by more than a factor of two, the PL FWHM and BA laser performance were found to improve with increasing temperature. This indicates that the FWHM is the more relevant PL optimization parameter. Figure 2 compares threshold current densities for 1.3- $\mu$ m BA lasers grown at two different temperatures with those for 1.2- $\mu$ m InGaAs lasers. The GaInNAs lasers grown at the higher temperature shows an improved threshold current density of 1.2 kA/cm² (0.8 kA/cm² when extrapolated to infinite length) and a slope efficiency as high as 0.25 W/A for a length of 1400  $\mu$ m. These lasers exhibit a T<sub>0</sub> value of 80 K.

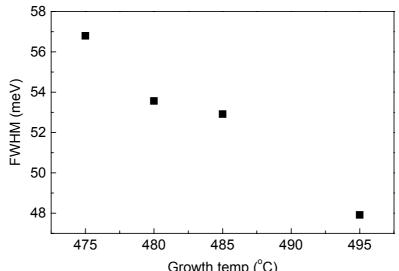
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Table 1. PL and BA laser characteristics of laser structures emitting at 1.2-1.3  $\mu m$ 

SQW Structure GaIn <sub>x</sub> N <sub>y</sub> As			$T_{grow}$	PL		BA laser	λ	$J_{th}$	Slope eff.	$T_0$
			th	Intensity	FWHM	length				(10-80°C)
X	у	nm	°C	(a.u.)	(meV)	(µm)	(nm)	(kA/cm <sup>2</sup> )	(W/A)	(K)
0.39	0	7.2	520	5700	30	800	1200	0.3	0.25	104
0.35	0.002	6.8	490	730	35	800	1200	1.9	0.2	77*
0.37	0.007	6.4	495	4	48	800	1270	1.7	0.25	80
0.37	0.006	7.2	475	13	55	800	1291	3.3	0.20	85*

<sup>\* 10 – 50 °</sup>C



Growth temp (°C) Fig. 1. Room temperature PL at 1.30-1.31  $\mu$ m from GaIn<sub>0.37</sub>N<sub>y</sub>As/GaAs SQWs of similar N content (y=0.006 - 0.007) and thickness (6.4 - 7.2 nm).

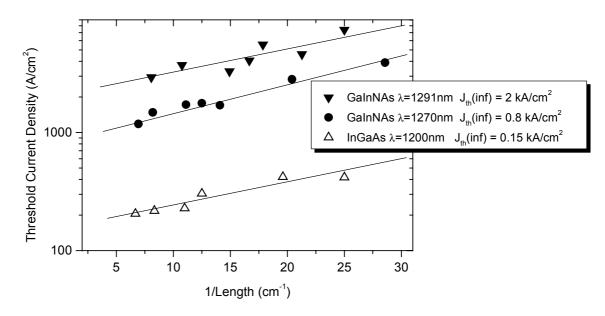


Fig. 2. BA laser threshold current densities as a function of inverse cavity length.